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Customer No.: 07278

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Kazuo Kasai, et al

Serial No.: 10/812,747

Group Art Unit: 1765

Filed: March 29, 2004

Examiner: VING, LAN

For: SILICON SUBSTRATE ETCHING METHOD AND ETCHING APPARATUS

STATUS REQUEST

Commissioner of Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

To date, we have received no communication or official action from the Examiner in charge of the above-identified patent application. Please let us know the status of this case.

Respectfully submitted,



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Dated: November 7, 2005

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